

An ELNES study of SiO₂ nanowires grown from a patterned reagent

Feng Wang,^{1,2} Marek Malac,^{1,2} R.F. Egerton,¹ Peng Li,¹ A. Meldrum,¹ and M.R. Freeman¹

¹Department of Physics, University of Alberta, Edmonton T6G 2J1, Canada

²National Institute for Nanotechnology, 9107 116th Street, Edmonton, T6G 2V4, Canada

Progress has been achieved recently in the synthesis and device application of SiO₂ nanowires, however isolating and manipulating freestanding nanowires is still challenging, and it is of great interest to grow them in a controlled fashion, so that no post-growth manipulation is needed for further measurement or device use [1]. We have developed a novel process to synthesize SiO₂ nanowires from a patterned reagent into arrays with tunable size and pitch, using electron-beam lithographic patterning of Fe-SiO₂ composite films [2]. First, stable iron nanoparticles embedded in SiO₂ matrix are grown onto Si₃N₄ membranes in an ultrahigh vacuum system [3]. Such composite samples are then patterned and etched, using hydrogen silsesquioxane (HSQ) negative-tone resist, giving circular HSQ (exposed) nanodots, 50 nm in diameter and a 1 μm pitch, covering the Fe-SiO₂ composite film. Taking advantage of the catalytic properties of the Fe particles, nanowires are grown from the patterned nanodots by annealing in a furnace reactor (in a N₂/H₂ atmosphere) as shown in Fig. 1. The number and diameters of the nanowires on each dot depend on those of the iron nanoparticles, which is controllable through the fabrication and patterning process [2].

Figure 2 shows a transmission electron microscope (TEM) image of a bundle of nanowires projecting from the substrate. The nanowires have a smooth surface and a closed end, in which a single iron particle is entrapped, indicating a gas-liquid-solid growth mode. A limited number of nanowires (Fig. 2, inset) were selected for analysis by electron energy-loss near-edge structure (ELNES) and nano-diffraction patterns (DP). The results are presented in Figs. 3 and 4; Auger spectra and images were also recorded for chemical analysis of the nanowires.

Electron energy-loss and Auger analysis showed that the nanowires contain silicon and oxygen; Spectra analysis carried out on individual nanowires was not affected by the presence of the substrate, as shown by the absence of the N-K edge in Fig. 3. The Si-L₂₃ edges of SiO₂ and Si differ in their fine structure and threshold energy [4], allowing us to exclude the presence of elemental Si in the nanowires. We have performed multiple-scattering calculations of the Si-L₂₃ edge (shown in Fig. 3) and O-K edge (not shown here) of SiO₂. These simulations give us confidence that the nanowires consist of SiO₂.

Pure iron is useful as high-activity catalyst but is susceptible to oxidation, which we sought to minimize by embedding the iron nanoparticles in a SiO₂ matrix. Absence of a postpeak at about 40 eV above the Fe-L₂₃ confirms that oxidation of iron is low [5]. However, our measured white-line ratio: L₃/L₂ = 2.9 ± 0.2, extracted by fitting the Fe-L₂₃ edges (shown in Fig. 4), indicates some chemical reaction [5], perhaps the formation of iron silicides at the surface, as expected by the vapor-liquid-solid model. Judged from the intensity profile of the DP (showing as a photographic negative in the inset of Fig. 4), bcc-Fe is the main phase; there is evidence of iron silicides but not iron oxides. No SiO₂ peaks were found, indicating the amorphous nature of the nanowires.

The exposure product of HSQ is Si_xO[6], which evidently provides the reagent source for the growth, since no nanowires appeared in areas covered with unexposed HSQ or the SiO₂ of the

matrix itself. The embedded iron nanoparticles act as a catalyst, after diffusing to the surface. We are developing a model for the growth process of the nanowires, on the basis of our microstructural and chemical analysis [2].

[1] R.S. Friedman et al., *Nature* **434** (2005) 1085.

[2] F. Wang, M. Malac, and R.F. Egerton, *Nano Lett.*, in preparation.

[3] F. Wang, M. Malac, A. Meldrum, R.F. Egerton, X. Zhu, Z. Liu, N. Macdonald, P. Li, C. Blois, and M.R. Freeman, submitted to *J. Appl. Phys.*

[4] G.A. Botton et al., *J. Appl. Phys.* **91** (2002) 2921.

[5] F. Wang, M. Malac and R.F. Egerton, *Micron*, in press.

[6] H. Namatsu et al., *Microelectronic Engineering*, **41-42** (1998) 331.

[7] This work was supported by *NRC*, *NSERC* and the *Killam Trust*.

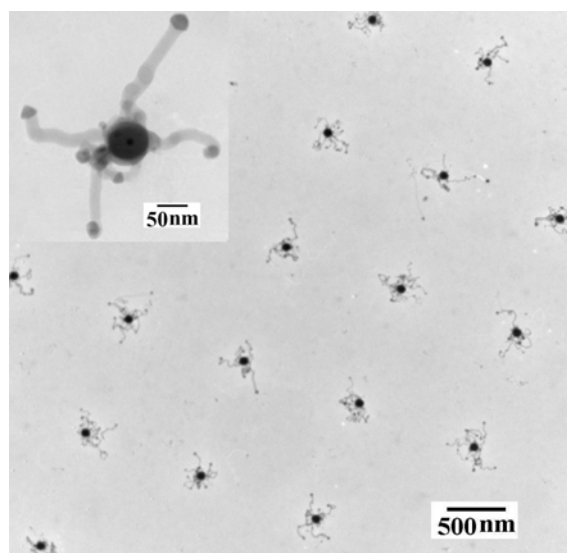


Fig. 1: SiO₂ nanowires on the Fe-nanodot array.

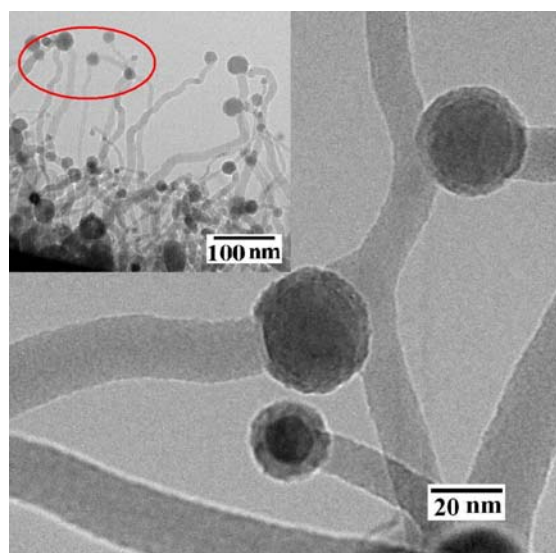


Fig. 2: SiO₂ nanowires and selected area for EELS analysis (inset).

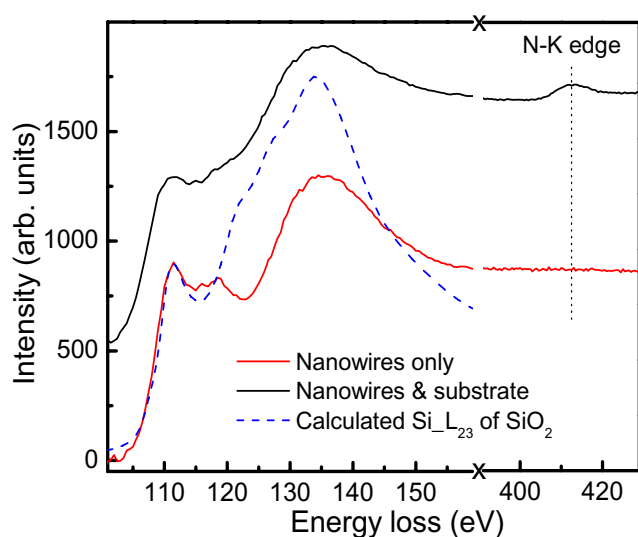


Fig. 3: Experimental Si-L₂₃ edges, compared with a Si-L₂₃ edge calculated for SiO₂.

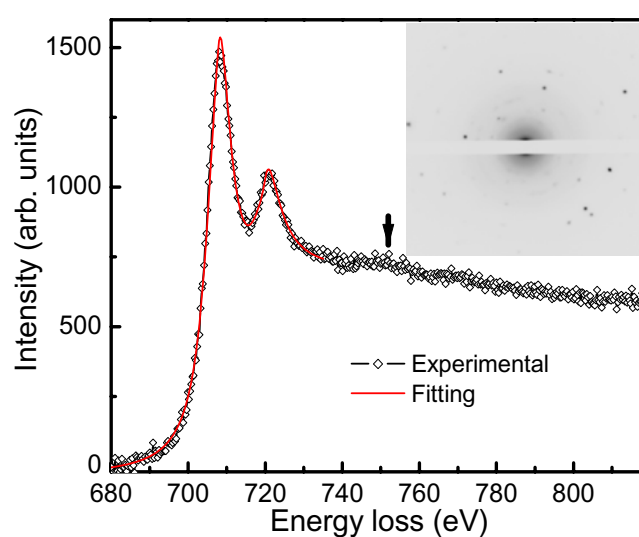


Fig. 4: Fe-L₂₃ edges with a computer fit and DP (inset) of selected individual nanowires.